



Our Docket No: 42P10058

**RESPONSE UNDER 37 C.F.R. § 1.116**  
**-- EXPEDITED PROCEDURE --**  
**EXAMINING GROUP 2800**

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:	)	
	)	
Han-Ming Wu et al.	)	Examiner: Nguyen, Hung
	)	
Serial No: 09/752,938	)	Art Unit: 2851
	)	
Filed: December 29, 2000	)	
	)	
For: Purging Gas from a	)	
Photolithography Enclosure	)	
Between a Mask Protective	)	
Device and a Pattern Mask	)	
	)	

RESPONSE TO OFFICE ACTION

Mail Stop AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

RECEIVED  
AUG - 1 2003  
TECHNOLOGY CENTER 2800

Sir:

In Response to the Final Office Action mailed on April 25, 2003, the Applicants respectfully request that the Examiner enter the following amendments and consider the following remarks.

FIRST CLASS CERTIFICATE OF MAILING

I hereby certify that I am causing the above-referenced correspondence to be deposited with the United States Postal Service as first class mail with sufficient postage on the date indicated below and that this paper or fee has been addressed to the Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

July 23, 2003

Date of Deposit

Krista Mathieson

Name of Person Mailing Correspondence

*Krista Mathieson*

Signature

July 23, 2003

Date